Tropel[®] FlatMaster[®] MSP Wafer Surface Metrology System

Advanced Optical Measurement System for Wafer Flatness, and Thickness Variation

CORNING

The ability to measure flatness, thickness, and thickness variation of semiconductor wafers is critical for wafer processing. Traditional contact probes and conventional interferometry systems are too slow or do not have the necessary accuracy over the full wafer surface area.

The Tropel FlatMaster® MSP Wafer (Multi-Surface Profiler) is a frequency stepping interferometer that provides fast and accurate metrology for wafers up to 300 mm. In seconds over 3 million data points are collected with sub-micron accuracy enabling total thickness and flatness characterization over the entire wafer surface.



MEASUREMENT

PARAMETERS

GLOBAL

- Thickness

- GBIR (TTV)

- GF3R (TIR)

- GFLR (NTV)

- GFLD (NTD)

- Bow, Warp, SORI



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	0.05	0.17	0.12	0.15	0.21	12
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0.02	0.05	0.09	0.08	0.21	0.12	0.19
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	0.04	0.07	0.14	0.17	0.17	0.21
		-		*	10-1	7
-		0.04	0.13	0.12	0.16	

Key Benefits:

LOCAL (SITE)

- SBIR (LTV)

- SBID (LDOF)

SF3D (LFPD)

SF3R (LTIR)

- SFLR (LTIR)

- SFQR (LTIR)

- SFQD (LFPD)

- Improves product quality, manufacturing yield and throughput
- Lowers manufacturing costs
- Increases process awareness and understanding
- Reduces time-to-market
- Increases customer satisfaction

Powerful:

- High resolution and accuracy for thickness across the entire wafer surface
- Capable of mapping sub-micron thickness changes in the wafer after processing (i.e. CMP, Epi)
- Large dynamic range
- Excellent reproducibility from operator to operator

Flexible:

• Measures a broad variety of material types and surface finishes

Easy to Use:

- Simply place the part on the system and measure
- Little or no fixturing required
- Intuitive recipe driven operation
- Suitable for production, quality control, or development

Tropel® FlatMaster® MSP Wafer Surface Metrology System Specifications

Field of View Z-Resolution Lateral Resolution Measurement Range (Z-axis)	FlatMaster MSP-150 150 mm (5.9 in) 1 nm (0.04 µin) 0.15 mm (0.006 in) Up to 300 mm (11.8 in)	FlatMaster MSP-200 225 mm (8.9 in) 1 nm (0.04 µin) 0.1 mm (0.004 in) Up to 300 mm (11.8 in)	FlatMaster MSP-300 305 mm (12.0 in) 1 nm (0.04 μin) 0.17 mm (0.007 in) Up to 300 mm (11.8 in)				
Measurement Time Measurement Method Measurement Data Points Materials Surface Finishes	30 seconds typical Frequency Scanning Interferometry Up to 3.1 million points per measurement Metals, polymers, ceramics, glass, and many other materials Fine-ground, lapped, polished, super-finished, and others						
Accuracy & Repeatability							
Flatness Parallelism Depth/Height**	Accuracy* 60 nm (2.4 μin) 75 nm (3.0 μin) 100 nm (4.0 μin)	Repeata 20 nm (c 20 nm (c 20 nm (c	bility* 5.8 μin) 5.8 μin) 5.8 μin)				
* Refers to instrument limited accuracy and reper ** Height/depth accuracy and repeatability are de	atability (1 sigma) as based on measurement of t ependent on part geometry; consult Corning Trop	raceable artifact. bel for more details.					
Tropel Metrology Software (TM	VIS™)						
Standard Parameters Report Layouts Data Management	Flatness, depth/height, parallelism, line profile, surface profile User-configurable including: open GL, 3-D, 2-D, line trace (X/Y, radial, diameter, circular), color contour, isometric, histogram, user-defined tolerances, pass/fail criteria Available in report layouts, also database, CSV and serial port,						
C C	optional export to industry standard database formats						
Environmental and Facility							
Temperature Rate of Temperature Change Vibration Isolation Humidity Power Air/Vacuum	15 °C to 25 °C (59 °F to 77 °F) < 0.5 °C per 4 hours (A change of ± 0.5 C (± 3.6 F) requires recalibration) Passive isolation included 5% to 95% relative humidity, non-condensing 100-240 VAC, 50/60 Hz, 4 Amp See facilities document						
System Dimensions (W x D x H) System Weight	160 cm x 103 cm x 150 cm (63 in x 40 in x 59 in) 390 kg (860 lb)						

Standard System Configuration

Computer Software Traceable Artifact

This product is covered by one or more U.S. patents. All specifications are subject to change. Tropel[®] is a Registered Trademark of Corning Incorporated. FlatMaster® is a Registered Trademark of Corning Incorporated. OpenGL[®] is a Registered Trademark of SGI. Windows® is a Registered Trademark of MicroSoft Corporation

Windows[®] based PC TMS[™] Analysis Software Included



For additional information about the FlatMaster® MSP System or other Tropel® Metrology Instruments, please contact:.

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